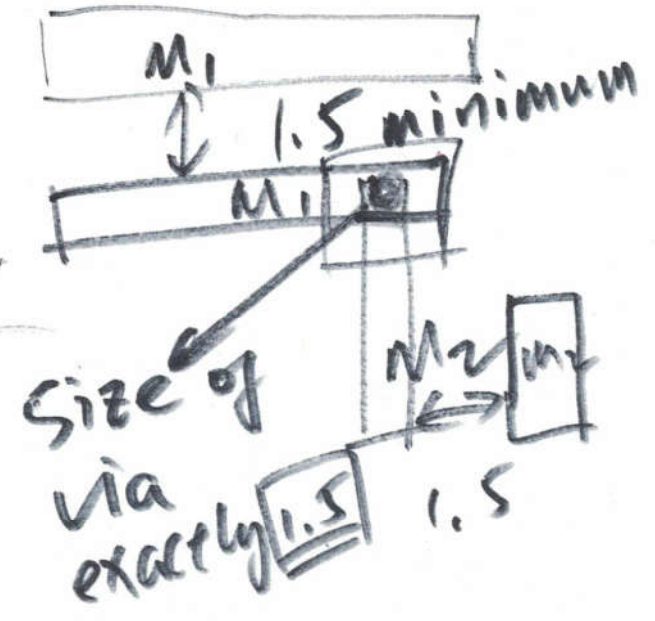
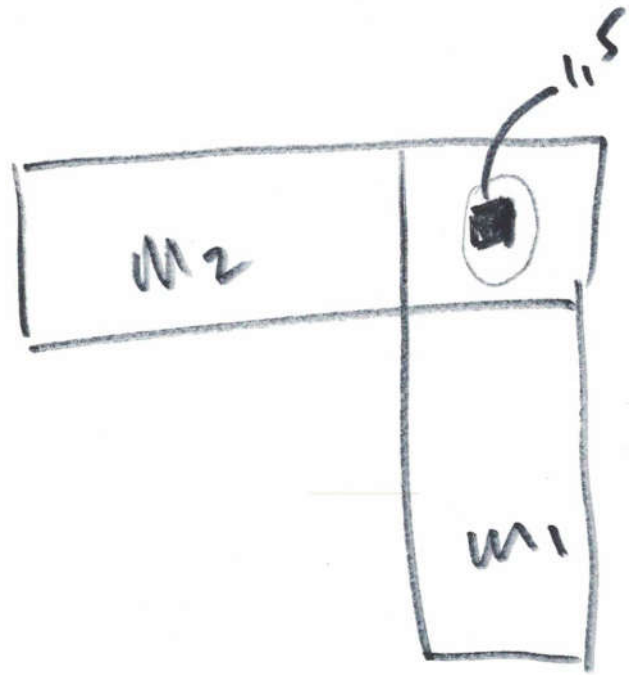


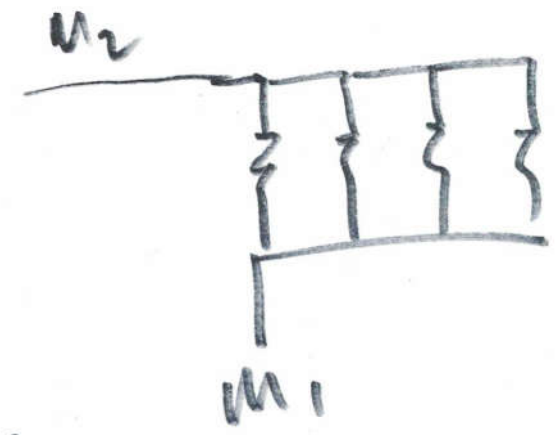
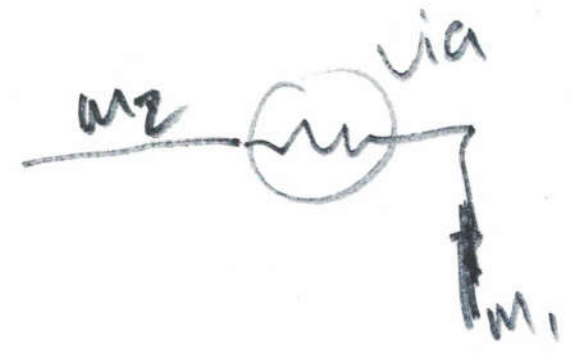
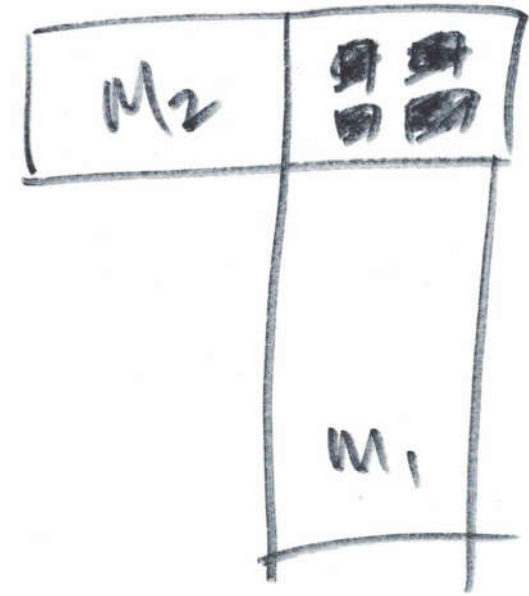
Electric VLSI
↓
Preferences
↓
Technology

$1\lambda = 300\text{nm}$
(lambda Rule)





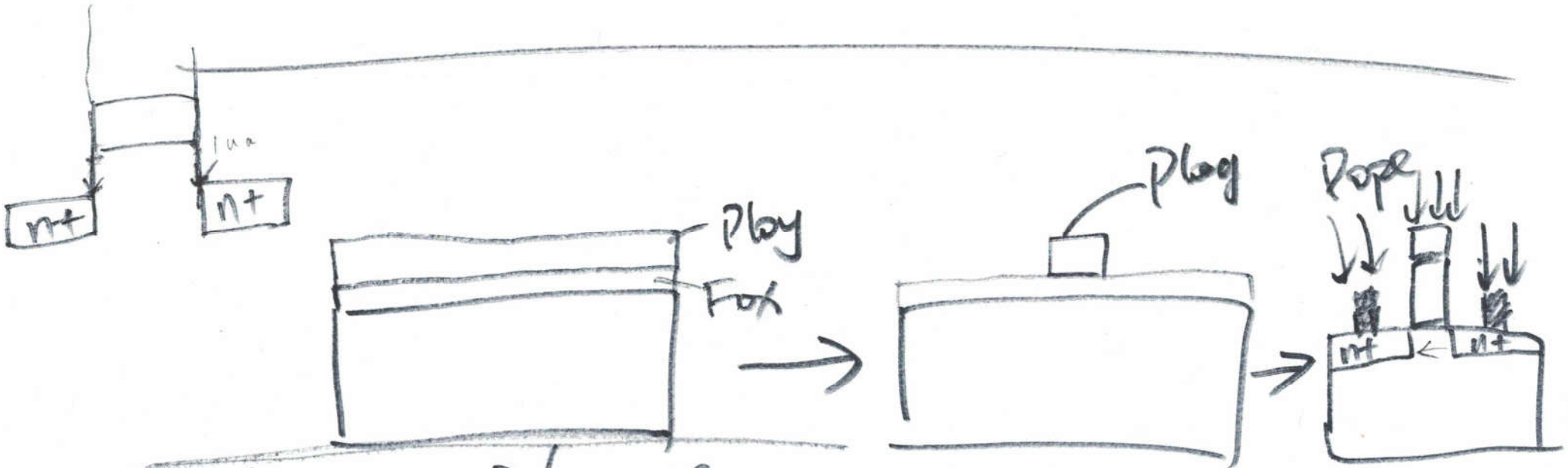
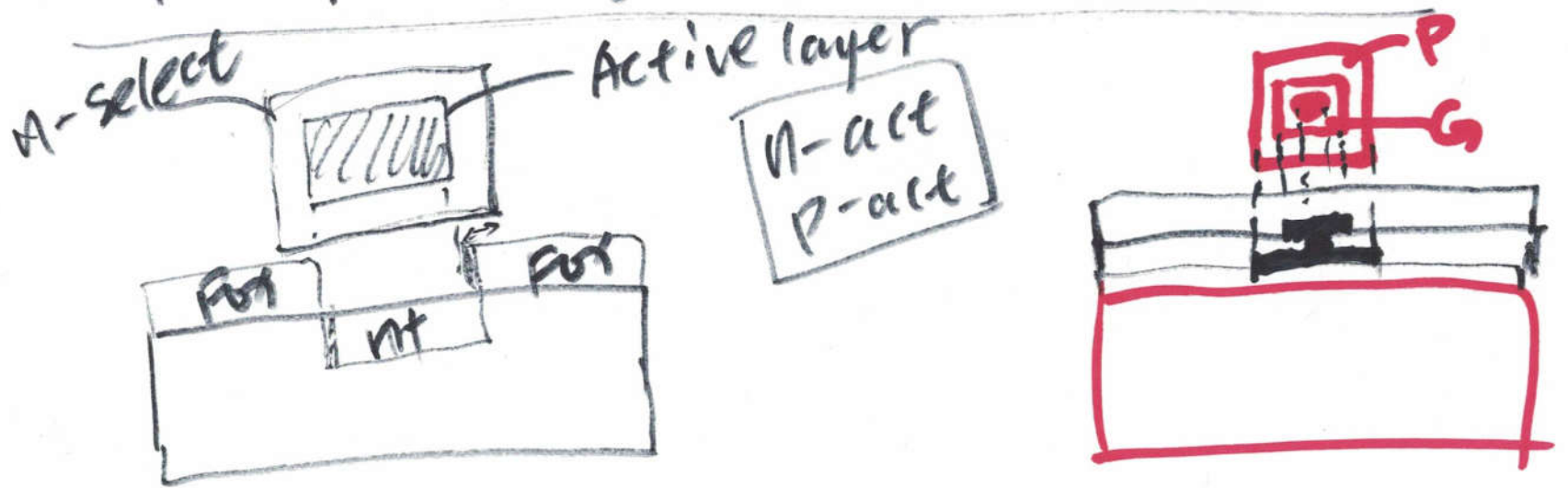
optimized



Benefits:

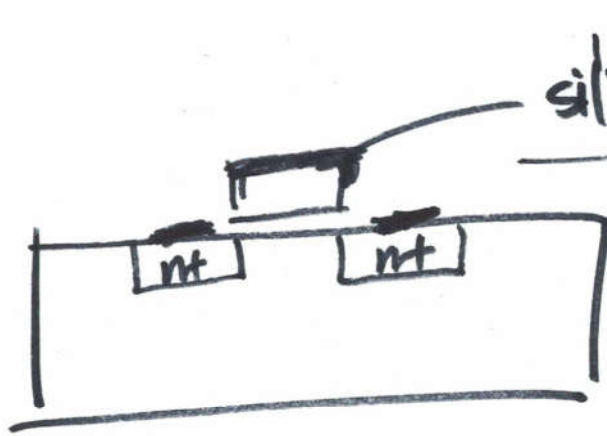
- ① lower resistance
- ② get some backup vias
- ③ Dive the current (lower the current)

The Active Layer Opens up the Fox



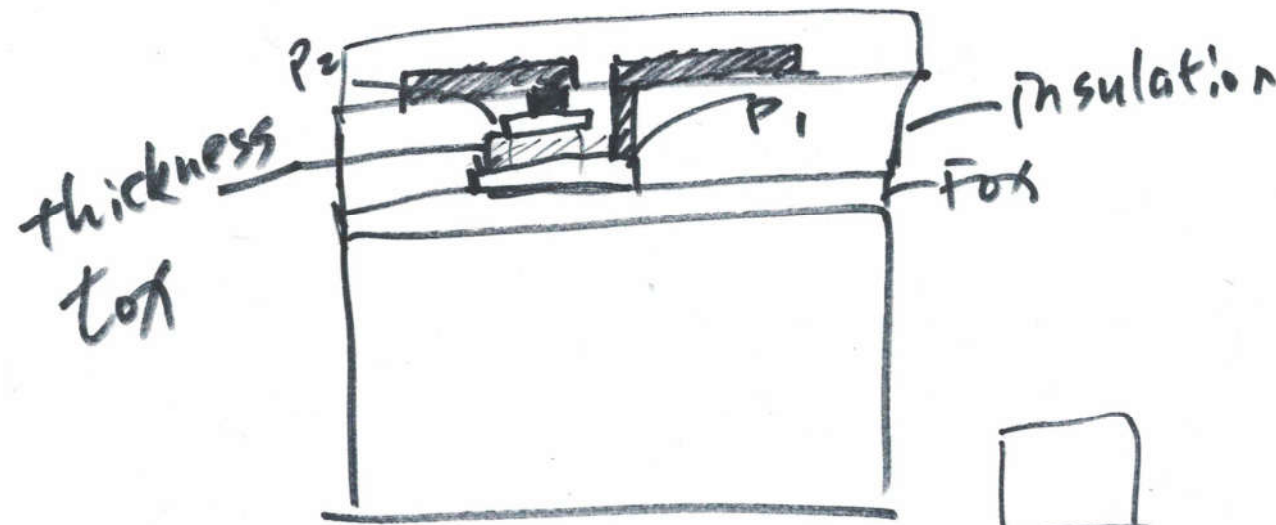
play $200 \Omega / \text{square}$
 nt $0.1 \Omega / \text{square}$

poly/nt are self-aligned



silicide (tungsten)

to reduce the resistance of poly



Given $\underline{C_{OX}} = \frac{\epsilon_r \cdot \epsilon_0}{t_{OX}}$

ϵ_r : permittivity of a dielectric material

ϵ_0 : permittivity of vacuum

$C_{OX} = C_{OX}' \cdot A$

50 nm technology, 10×10
(P_1 and P_2)

$\underline{C_{OX}} = \underline{C_{OX}'} \times (50 \text{ nm} \times 10) \times (50 \text{ nm} \times 10)$
 $\hookrightarrow 25 \text{ fF}/\mu\text{m}^2$